

Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

Listing of Claims:

1. (Currently amended) A drop ejector, comprising: a flow path in which fluid is pressurized to eject drops from a nozzle opening in a plane, and proximate the nozzle opening, a plurality of projections ~~extending from the plane of the nozzle opening, wherein the height of the projections~~ is substantially equal to the plane of the nozzle opening.
2. (Original) The drop ejector of claim 1 wherein the nozzle opening is surrounded by projections.
3. (Original) The drop ejector of claim 1 wherein the projections are posts.
4. (Original) The drop ejector of claim 1 wherein the projections are wall-shaped.
5. (Original) The drop ejector of claim 1 wherein the projections are arranged in a pattern.
6. (Original) The drop ejector of claim 5 wherein the pattern defines an array of rows and columns.
7. (Original) The drop ejector of claim 5 wherein the pattern defines an arc.
8. (Original) The drop ejector of claim 5, wherein the pattern defines concentric ink-collection spaces.

9. (Original) The drop ejector of claim 1 wherein the projections have a width that is about twice the nozzle opening width or less.

10. (Currently amended) The drop ejector of claim 1 further comprising the nozzle opening having a perimeter and a nozzle opening width, wherein the projections are no closer to the perimeter of the nozzle opening than about 20% of the nozzle opening width.

11. (Original) The drop ejector of claim 1 wherein the spacing between projections is about twice the nozzle width or less.

12. (Original) The drop ejector of claim 1 wherein the number of the projections is four or greater.

13. (Canceled)

14. (Currently amended) A drop ejector, comprising: a flow path in which fluid is pressurized to eject drops from a nozzle opening in a plane, and proximate the nozzle opening, a plurality of projections. ~~The drop ejector of claim 1~~ wherein the height of the projections is below the plane of nozzle opening.

15. (Canceled)

16. (Currently amended) The drop ejector of claim 14 wherein the nozzle opening and projections are defined in a common body.

17. (Original) The drop ejector of claim 16 wherein the body is a silicon material.

18. (Currently amended) The drop ejector of claim 14 including a channel proximate the

projections.

19. (Currently amended) The drop ejector of claim 14 including a vacuum source or wicking material proximate the projections.

20. (Currently amended) The drop ejector of claim 14 wherein the nozzle opening is disposed in a well and the well includes said projections.

21. (Currently amended) The drop ejector of claim 14 wherein the nozzle opening is disposed on a platform and the projections are disposed proximate the platform.

22. (Currently amended) The drop ejector of claim 14 including a plurality of nozzle openings and a plurality of projections proximate each of the nozzle openings, said nozzle openings and said projections defined in a common body.

23. (Currently amended) The drop ejector of claim 14 wherein the nozzle opening width is about 200 micron or less.

24. (Currently amended) The drop ejector of claim 14 including a piezoelectric actuator.

25. (Canceled)

26. (Currently amended) The drop ejector of claim ~~25~~14 wherein the spacing between said ~~posts~~projections is about 10% of the nozzle opening width or greater and twice the nozzle opening width or less.

27. (Currently amended) The drop ejector of claim ~~25~~14 wherein the ~~posts~~projections have a width that is about twice the nozzle opening or less.

28.-31. (Canceled)

32. (New) The drop ejector of claim 14 wherein the projections are arranged in a pattern.

33. (New) The drop ejector of claim 32, wherein the pattern defines concentric ink-collection spaces.

34. (New) The drop ejector of claim 1 wherein the nozzle opening is disposed in a well and the well includes said projections.

35. (New) The drop ejector of claim 1 wherein the spacing between said projections is about 10% of the nozzle opening width or greater and twice the nozzle opening width or less.

36. (New) The drop ejector of claim 1 wherein the nozzle opening and projections are defined in a common body.

37. (New) The drop ejector of claim 36 wherein the body is a silicon material.

38. (New) The drop ejector of claim 1 including a channel proximate the projections.